SUBSTRATE TRANSPORT APPARATUS AND METHOD FOR MANUFACTURING MAGNETIC RECORDING MEDIUM

ABSTRACT OF THE DISCLOSURE

A substrate transport apparatus comprises chambers connected to each other through a gate valve, a transport mechanism configured to open the gate valve and to transport a carrier between the chambers along a transport path, a sensor configured to detect the carrier before the carrier reaches a stop position in the chamber, and a controller configured to cause the gate valve to start closing based on the detection signal from the sensor.

FIG. 3